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# Design and performance of a multilayered mirror monochromator in the low-energy region of the VUV

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For the energy region from tens to hundreds of electron volts, the multilayered mirror (MLM) monochromator has never been realized due to the difficulty of reducing the background noise of the total reflection component, in spite of its usefulness in synchrotron radiation experiments. In this work, a double-crystal-type MLM monochromator equipped with a thin-film filter has been designed on the basis of trial fabrication of MLMs, the driving system and of Mo/Si and Mo/C multilayers. The design has been evaluated by calculation. It is shown that by using the MLM monochromator with an appropriate thin-film filter, the practical monochromator can reduce the background noise.

**Keywords:** multilayered mirror monochromator, thin-film filter, mirror monochromators.

## 1. Introduction

Studies of synchrotron-radiation-stimulated processes such as etching and chemical vapour deposition (CVD) began about 12 years ago (Urisu & Kyuragi, 1987) and are still attracting much interest from many researchers. The vacuum ultraviolet (VUV) photons in synchrotron radiation can excite almost all the electronic states of molecules, so a large variety of chemical reaction channels different from that in the usual thermal-CVD are expected to be opened by synchrotron radiation irradiation. In particular, core electrons, which cannot be excited using lasers, are efficiently excited by the VUV photons in synchrotron radiation. The excitation-energy dependence of a photochemical reaction is important basic data. However, it has not been sufficiently investigated in the VUV region, because of the difficulty in obtaining energy-tunable monochromated light with sufficient photon flux ( $>10^{13}$  photons  $s^{-1}$ ) in the VUV region.

A multilayered mirror (MLM) monochromator is already in use in the high-energy region of the VUV (Barbee *et al.*, 1987). Concerning the low-energy regions, one of the present authors previously tried to use an MLM as a dispersion element in synchrotron-radiation-stimulated experiments. However, this was unsuccessful due to the difficulty in removing the background noise, consisting of total reflection components appearing at less than a few tens of eV. Therefore, in this work, we have designed a double-crystal-type MLM (Golovchenko *et al.*, 1981; Murata *et al.*, 1992) monochromator combined with an appropriate thin-film filter. The design is based on the trial fabrication of MLMs

and the driving system for them. We have found that the low-energy background noise is sufficiently removed by using the MLMs at low incident angles combined with a carbon or molybdenum filter.

## 2. Design of the monochromator and mirrors

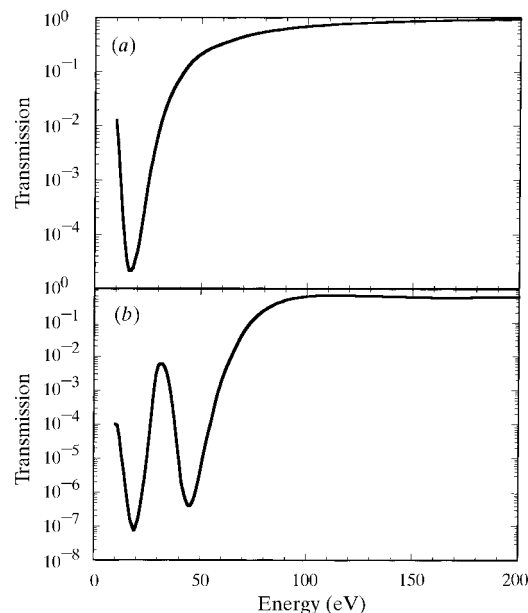
### 2.1. Monochromator

We adopted the monochromator driving system proposed by Golovchenko *et al.* (1981). The centres (*A* and *B*, respectively) of the first and the second MLMs are set on the *XY* and *YZ* lines which form a rigid right angle *XYZ*, with the first MLM parallel and the second perpendicular to the *XY* and *YZ* lines, respectively. A pulsed motor drive slides the apex (*Y*) of the *XYZ* linearly, keeping the rotational angle ( $\theta$ ) of the second mirror fixed. The first mirror is rotated around the centre (*B*) of the second mirror so that it translates the apex (*Y*) of the *XYZ* linearly, so that it translates the apex (*Y*) of the *XYZ* linearly, keeping the rotational angle ( $\theta$ ) of the second mirror fixed. It is designed so that the first and second mirrors move with each other in an appropriate way. The driving system is also effective for removing the higher-order photons. The present prototype monochromator has been designed as the incident angle to the MLMs. The mechanical linkage and driving system have been designed so that the beam incident angle can be adjusted at small angles as small as possible. The present prototype monochromator driving system has successfully covered an incident beam angular range ( $\theta$ ) of 10–80°.

### 2.2. MLMs

The important photon energy region for the experimental investigation of synchrotron radiation processes, especially of the core-electron excitation processes, is from a few tens to hundreds of electron volts. In the present work our attention was focused on the region between 60 and 120 eV, a region for which fairly high reflectivity is obtained by using Mo/Si (for 60–90 eV) and

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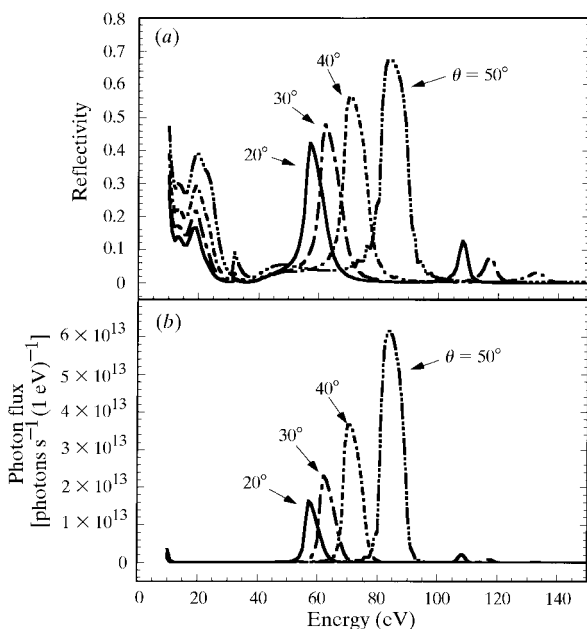
**Figure 1** The calculated transmission for (a) a 100 nm-thick carbon filter and (b) a 100 nm-thick molybdenum filter.

**Table 1**  
Specifications of optical components.

Component	Specifications	
Mo/Si MLM	Substrate	Si wafer (40 × 40 mm)
	Number of layers	20
	Period, $d$	12.5 nm (12.4 nm)†
	Thickness ratio, Mo/Si	3/7 (3.25/6.75)†
	Interface roughness, $\sigma$	(0.4 nm)†
Mo/C MLM	Substrate	Si wafer (40 × 40 mm)
	Number of layers	50
	Period, $d$	7.5 nm (7.9 nm)†
	Thickness ratio, Mo/C	1/1 (5.5/4.5)†
	Interface roughness, $\sigma$	(0.4 nm)†

† Values determined by fitting to the observed Cu  $K\alpha$  line diffraction curves.

Mo/C (for 85–120 eV) MLMs. This energy region includes the core-electron binding energies of Al (2s: 119 eV; 2p: 74 eV) and Si (2p: 103 eV), which are important materials in semiconductor processes. To reduce the background noise in the low-energy region due to the total reflection, it is necessary to use the MLM at low incident angles. The Mo/Si and Mo/C MLMs were therefore designed so that they could cover the Al 2s and 2p and Si 2p binding energies in the incident angle range of 10–50°. Furthermore, the detailed structural parameters have been determined so that the reflectivity is high and the reflectivity is periodic. Both Mo/Si and Mo/C MLMs have structural parameters listed in Table 1 have been determined using the Cu  $K\alpha$  line (Japan Synchrotron Radiation Corporation ART). The difference between Mo and Si layer roughness characterized by  $\sigma$  (Porteus, 1960),  $\sigma$ , determined from the data, are listed in Table 1.



**Figure 2**  
(a) Calculated reflectivity for the Mo/Si MLM and (b) output photon flux of the monochromator using Mo/Si MLMs plus C filter for a 100 mA ring current and a  $16.56 \times 12.79$  mrad<sup>2</sup> acceptance angle of the pre-mirror, assuming that the monochromator is set up in the beamline BL-4A1 of the UVSOR.

### 2.3. Thin-film filters

The transmission characteristics of the thin-film filter have been calculated for several materials and it has been found that carbon and molybdenum are useful for reducing the background noise at energies below 70 eV. The transmission spectra calculated for 100 nm-thick carbon and molybdenum film filters are shown in Figs. 1(a) and 1(b), respectively.

### 3. Performance of the monochromator

The performance of the MLM monochromator, designed as described above, was evaluated by calculating what the basic characteristics, such as output photon flux, resolution, monochromaticity and tuning range, would be if the monochromator were set up as part of the beamline (BL4A1) of the synchrotron radiation storage ring at the UVSOR. In this beamline, the beam emitted from the bending-magnet source point is reflected by an elliptical pre-mirror at an incidence angle of 4°. The horizontal and vertical pre-mirror are 50 cm and 3 cm, respectively, downstream from the source point. The size of about 6.1 m × 0.5 m is used at about 6.1 m downstream from the source point. The size of about 0.5 × 0.5 m is calculated for a monochromator. The recurrent equation (Spiller, 1981) for the Mo/Si MLMs were first calculated by using the structural parameters listed in Table 1, as shown in Fig. 2(a) for the Mo/Si case. It is known that extremely large total-reflection components appear at less than 40 eV in the case of Mo/Si.

The output beam photon fluxes calculated for various incident angles are shown in Fig. 2(b) for the case of Mo/Si MLM plus C filter. It is clearly shown that the filter drastically reduces the low-energy background noise. It is less than 1% (3%) of the main flux, where the value in parentheses is for the case of Mo/C MLM plus Mo filter. The higher-order photons background noise is less than 4% (0.1%). The calculated photon flux is  $1 \times 10^{14}$  to  $5 \times 10^{14}$  photons s<sup>-1</sup> ( $3 \times 10^{13}$  to  $4 \times 10^{13}$  photons s<sup>-1</sup>) and the resolution is 5–9 eV (2–4 eV) FWHM. The calculated results are similar to those obtained with a typical undulator. Given that the MLM monochromator can select the photon energy continuously and that the mixing of higher-order photons is small, it is suggested that the present monochromator will be better than an undulator for use in synchrotron radiation experiments. We conclude from this work that the background noise due to the total reflection, which prevented the MLM monochromator from being used in the VUV low-energy region, can be sufficiently reduced by using double-crystal-type MLMs at low incident angles combined with a carbon or molybdenum thin-film filter.

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